

Monolithic Preamplifiers for Low-Capacitance Detectors

when an FET is not an FET
when a resistor is not a resistor

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OUTLINE:

- Capacitive matching of detector and input transistor
- Design of DC feedback circuit
- Results on CMOS preamplifiers
- Results on Bipolar preamplifiers

Capacitive match

1. Constant current density (discrete FETs)

$$\frac{g_m}{C_{gs}} = \omega_T, \text{ constant}$$

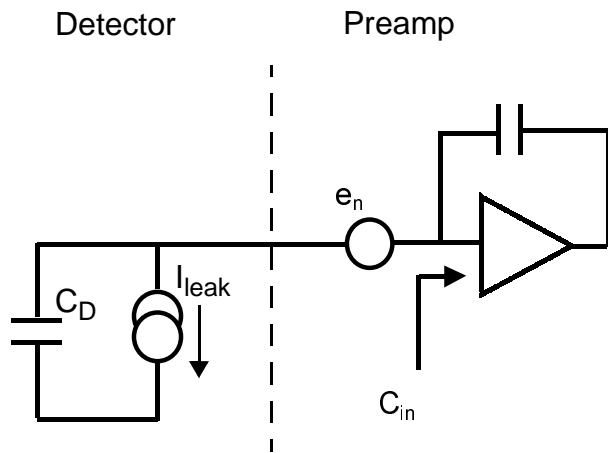
$$ENC = K \cdot \frac{C_D + C_{gs}}{\sqrt{g_m}} = K' \cdot \frac{C_D + C_{gs}}{\sqrt{C_{gs}}}$$

$$\left(\frac{d}{dC_{gs}} ENC = 0 \right) \Rightarrow C_{gs} = C_D$$

2. Constant drain current (monolithics)

Strong inversion (S.I.)	Weak inversion (W.I.)
$g_m = \sqrt{\frac{2\mu I_D C_{gs}}{L^2}}$	$g_m = \frac{I_D}{nU_T}, \text{ indep. of } C_{gs}.$
$ENC = \frac{K(C_{gs} + C_D)}{g_m} = K' \left(C_D C_{gs}^{-\frac{1}{4}} + C_{gs}^{\frac{3}{4}} \right)$	$ENC = K(C_D + C_{gs})$
$\frac{d}{dC_{gs}} ENC = 0 \Rightarrow C_{gs} = \frac{C_D}{3}$	$C_{gs} \rightarrow 0 \text{ -- but this brings device into S.I.}$
	optimum when $C_{gs} = \frac{2I_D L^2 C_{ox}}{K(3U_T)^2} \text{ S.I. - W.I border}$

Series Noise Matching



$$ENC = \frac{K_1 e_n (C_D + C_{in})}{t_s}$$

$$e_n = \left(\begin{array}{l} \frac{4kT\Gamma}{g_m} \quad \text{thermal} \\ \frac{4kTK_F}{C_{gs}} \quad 1/f \end{array} \right)$$

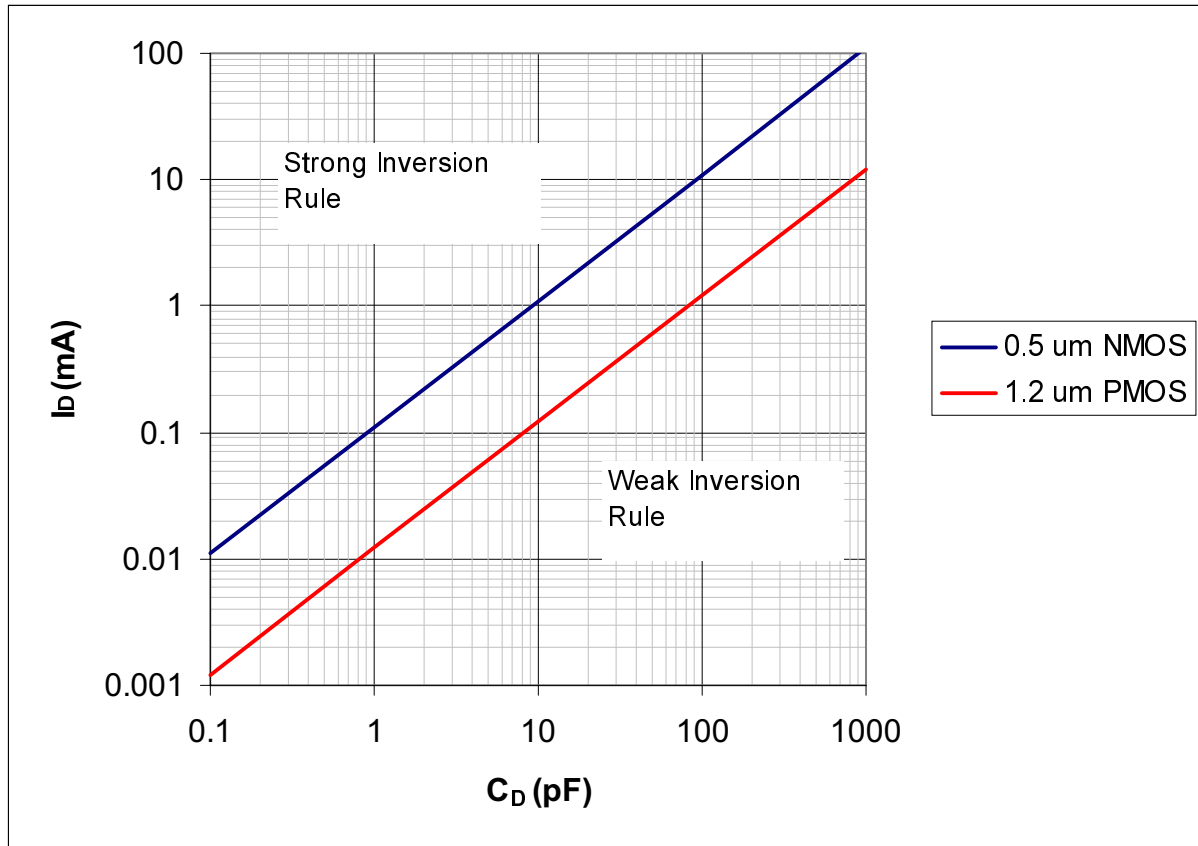
Ideal:

$$C_{in} = 0$$

$$e_n = 0 \quad \text{or} \quad g_m = \infty$$

→ highest f_T

Minimum current for S.I. capacitive match



Capacitive match -- Example

0.5 μm NMOS input device

$C_D = 10$ pF, $I_D = 0.2$ mA

Conventional $C_D/3$ match gives $W = 1543$ μm .

$g_m = 5$ mS

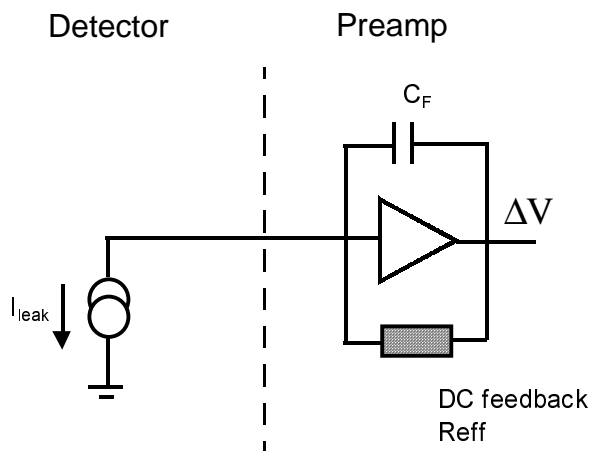
$C_{gs} + C_D = 13.3$ pF

Sizing device to W.I. - S.I. border gives $W = 281$ μm .

$g_m = 5$ mS

$C_{gs} + C_D = 10.6$ pF

Parallel Noise Management



$$ENC_{par} \sim 1/R_{eff}$$

$$\Delta V = I_{leak} \cdot R_{eff}$$

Ideal:



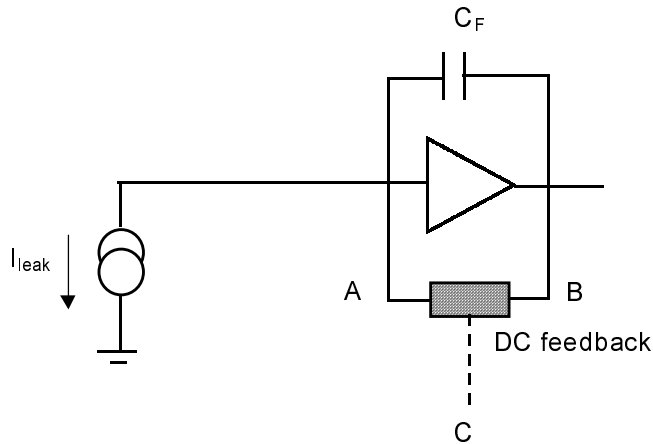
$$R_{eff} = 2kT/qI_{leak}$$

→ lowest ΔV with no noise penalty

$$\tau_{decay} = R_{eff} \cdot C_F$$

→ can effect gain if $\tau_{decay} \sim \tau_{shaper}$

DC Feedback

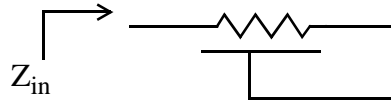


Feedback type	Circuit	$R_{eff} (I_{leak} = 0)$	Advantages/ Disadvantages
Physical resistor	A $\text{---} R \text{---}$ B	R	+ simple - hard to make large R - parasitic C - doesn't adjust to I_{leak}
MOS switch	A --- MOS --- B C(pulse)	$\frac{1}{C_F \cdot f_{reset}}$	+ simple - dead time - switch noise
Triode MOS	A --- MOS --- B C Bias	$\frac{1}{\beta \cdot (V_{gs} - V_T)}$	+ compact + adjusts to I_{leak} - nonlinear
Feedback g_m	A --- OpAmp --- B g_m C (Vref)	$\frac{1}{g_m}$	+ adjusts to I_{leak} - complex - excess noise - nonlinear
Attenuating current mirror	A --- OpAmp --- B $A_i \ll 1$	$\frac{R}{A_i}$	+ aux. output for PZC - doesn't adjust to I_{leak}

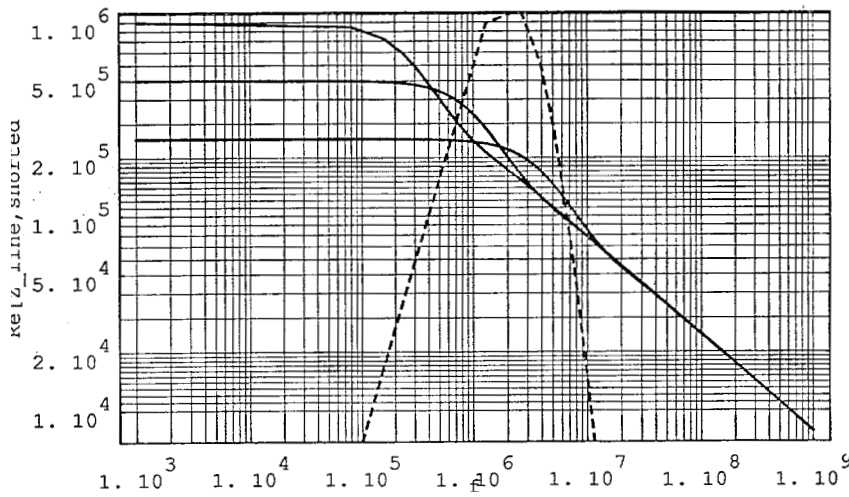
Resistor parasitic capacitance

For implanted resistor in MAXIM process, parasitic resistance is 1.3 fF/kΩ.

$$i_n^2 = \frac{4kT}{Re\{Z_{in}\}}$$

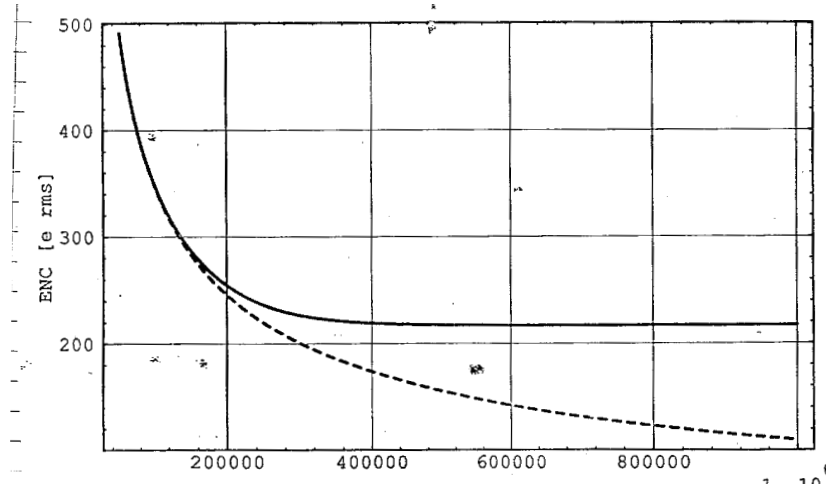


Real part of impedance of a shorted diffusive line



R=50 kΩ/section
C=0.65 pF/section
250 kΩ, 500kΩ, 1MΩ

ENC contribution of the diffusive feedback line

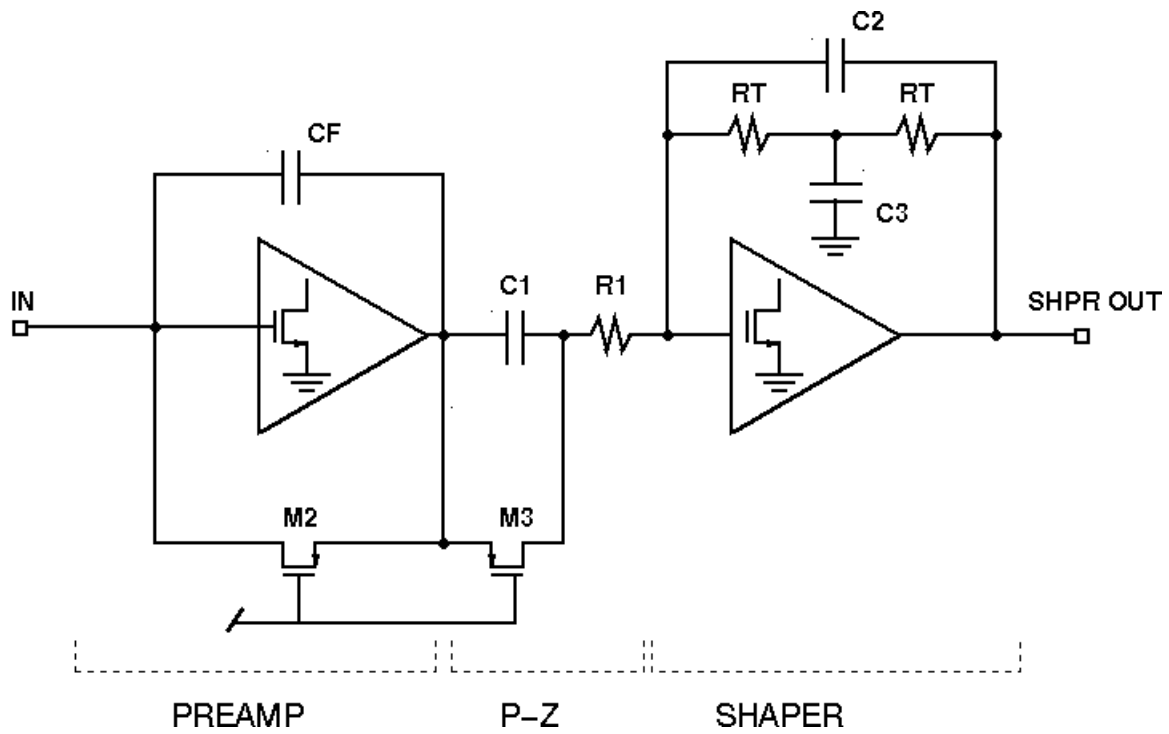


R=250K, Ctot=0.32pF

H(s)=1/(1+s tau)^4 tau=12 ns tpeak=30 ns



Adaptive Pole-Zero Cancellation



$$C_F R(M_2) = C_1 R(M_3)$$

$$V_G(M_2) = V_G(M_3)$$

$$V_S(M_2) = V_S(M_3)$$

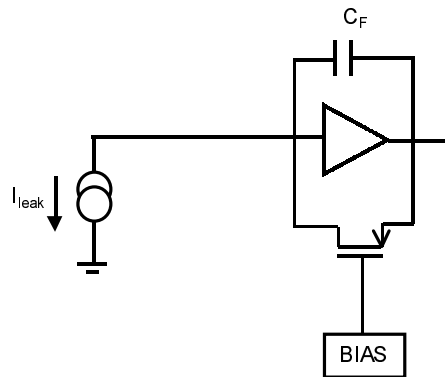
$$V_D(M_2) = V_D(M_3)$$

MOS Resistor

Behavior with $I_{leak} = 0$:

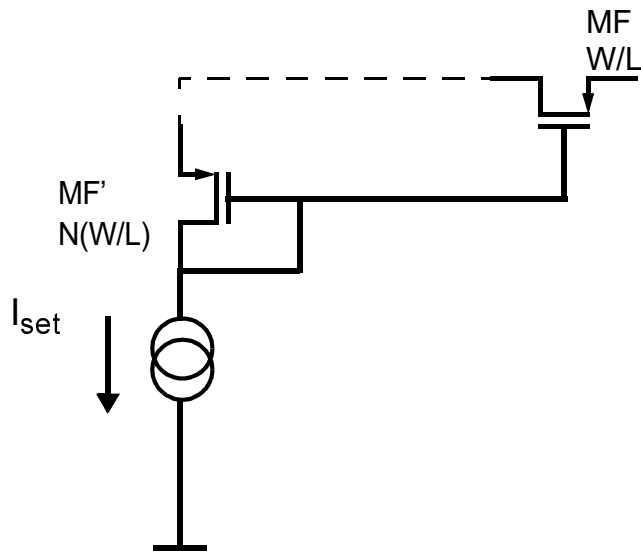
Strong inversion (S.I.)	Weak inversion (W.I.)
$I_d = \frac{\beta}{2} \cdot (V_{GS} - V_T)^2 \cdot V_{DS}$	$I_d = I_{do} e^{\frac{qV_{GS}}{nU_T}} \left(1 - e^{-\frac{V_{DS}}{U_T}} \right)$
$R = \frac{1}{\beta \cdot (V_{GS} - V_T)}$	$R = \frac{U_T \cdot e^{-\frac{qV_{GS}}{nU_T}}}{I_{do}}$

With I_{leak} and feedback:



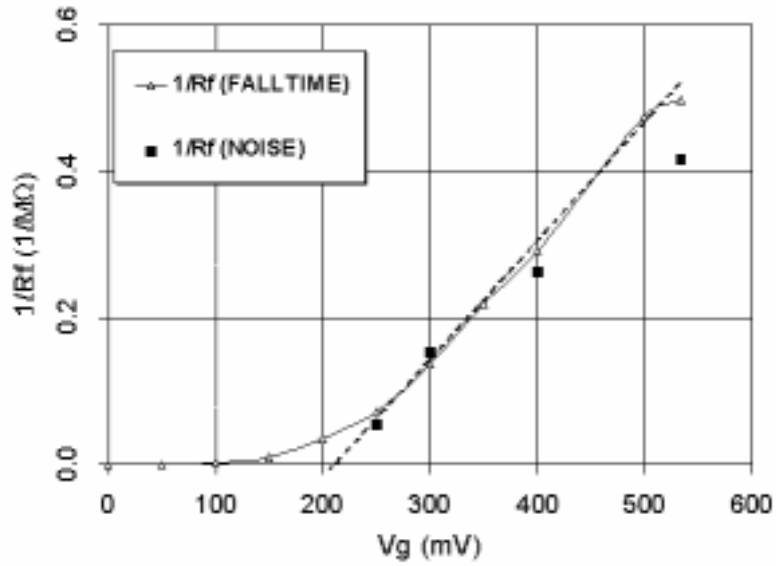
Strong inversion (S.I.)	Weak inversion (W.I.)
$R = \frac{R_0}{1 + \beta R_0^2 I_{leak}}$	$R = \frac{U_T}{I_{leak} + I_{do} e^{\frac{qV_{GS}}{nU_T}} \cdot e^{-\frac{V_D}{U_T}}}$ <p>→ current controlled!</p>

Bias circuit for MOS feedback resistor

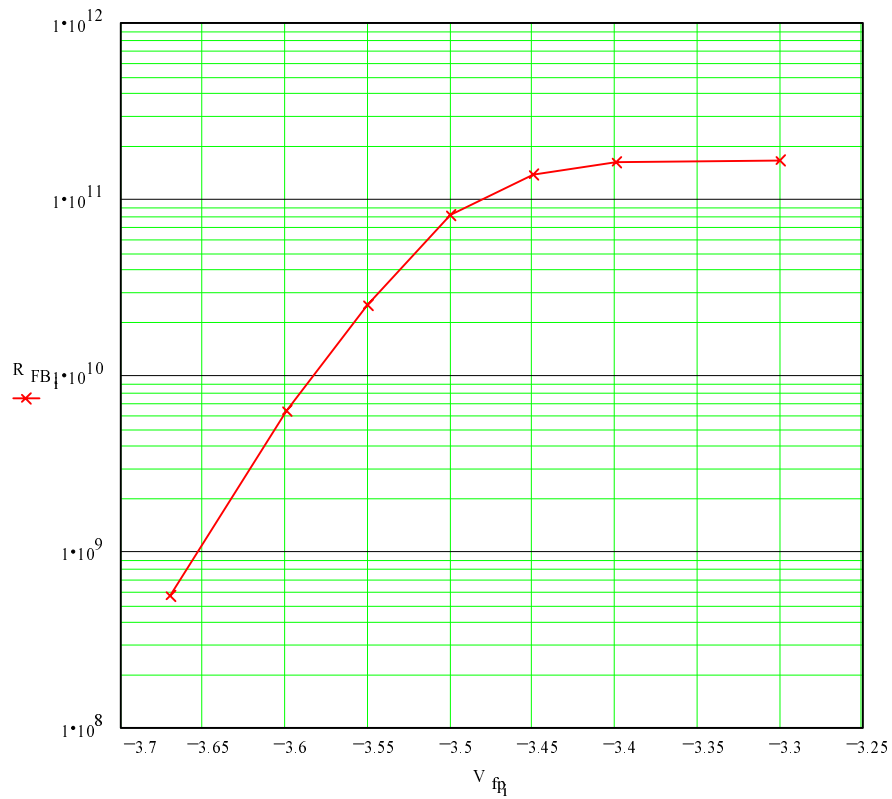


MF	MF'	R_{MF}
S.I.	S.I.	$\sqrt{\frac{N}{2K'(W/L)I_{set}}}$
W.I.	W.I.	$\frac{NU_T}{I_{set}}$
S.I.	W.I.	$\frac{1}{K' \frac{W}{L} \left(nU_T \cdot \ln \left[\frac{I_{set}}{I_0(W/L)N} \right] \right)}$

MOS Resistor in Strong Inversion:



MOS Resistor in Weak Inversion



Low-capacitance preamplifiers compared

	Bipolar MAXIM SH-Pi	CMOS “Tracker” HP 1.2μm	CMOS “X-ray” HP 1.2μm AMS 1.2μm	
Input device	npn	NMOS 250/1.2	PMOS 100/1.2	PMOS 82/1.2
Current	9μA	400 μA	1.2 mA	1.2 mA
gm	0.17 mS	3.5 mS	2.1 mS	1.9 mS
Cin		400 fF	190 fF	130 fF
Intended C _D	0.8 pF	0.8 pF	0.1 pF	0.1 pF
Feedback	Implanted Resistor	PMOS 3/20 μm	PMOS 3/3 μm	PMOS 3/3 μm
RF	250 KΩ	6 MΩ	280 MΩ	1 GΩ
Parasitic C	0.32 pF	0.10 pF	0.016 fF	0.016 fF
CF	100 fF	100 fF	15 fF	15 fF
Shaper	50 ns internal	50 ns internal	1 - 20 μs external	1 - 20 μs external